



Target Surfacing System

Leica EM TXP – Optimized Preparation Prior to Ion Milling System e.g. EM RES101 and EM TIC020

- Complete mechanical preparation system prior to Ion Milling
- Accurate location and preparation of microtargets
- Multifunctional machine processing – hole/sawing, grinding, polishing
- Continuous observation with a stereo microscope
- Reduced process time

Living up to Life

Leica
MICROSYSTEMS